

WHAT IS CLAIMED IS:

1. A test fixture, comprising;
 - 5 a table moveable in a first direction, wherein the table is adapted to secure a substrate embodying a trace conductor having opposing ends;
 - a probe pin moveable in two directions perpendicular to the first direction, wherein the probe pin is adapted to contact a first one of the opposing
 - 10 ends.
2. The test fixture of claim 1, further comprising a probe needle adapted to contact a second one of the opposing ends.
- 15 3. The test fixture of claim 2, further comprising a test device for sending and receiving signals to the probe needle and the probe pin.
4. The test fixture of claim 1, wherein the probe pin moves along axes parallel to and perpendicular to a planar surface on which said first one of the opposing ends is arranged
- 20 for contacting an upwardly extending distal end of the probe pin with a downwardly extending said first one of the opposing ends.
5. A test fixture, comprising:
 - 25 a pin retainer for retaining an upwardly extending pin;
 - a semiconductor substrate retainer having a trace conductor with one end of the trace conductor arranged above the pin; and

15. The method of claim 13, wherein after said moving steps, further comprising:

contacting a probe needle to an upwardly extending terminal end of the trace
conductor opposite the downwardly extending terminal end;

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applying electrical stimulus to the probe needle and the pin; and

measuring a response.

10 16. The method of claim 13, further comprising:

transmitting an electrical pulse along the trace conductor;

measuring a time delay of an ensuing reflected pulse; and

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determining from the delay time a location of high resistance defect in the trace
conductor as either residing inside or outside the substrate.

17. The method of claim 15, wherein said measuring comprises measuring electrical
20 resistance of the trace conductor between the probe needle and the pin.

18. The method of claim 14, wherein said removing comprises grinding the integrated
circuit.

25 19. The method of claim 14, wherein said holding comprises retaining the outer
periphery of the substrate above the table by securing opposed outer portions of the
substrate between a moveable sliding push plate and elongated walls mounted to the
table.

30 20. The method of claim 15, wherein said contacting the probe needle comprises
using a magnifying lens for aligning and contacting the probe needle.